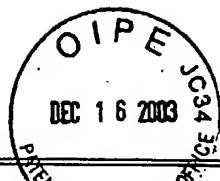




FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 03560.003317	APPLICATION NO. 10/600,763				
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)		APPLICANT NORIO OHKUMA					
September 23, 2003		FILING DATE June 23, 2003	GROUP Unassigned				
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
M	6,113,222	09/2000	Ohkuma				
M	6,128,052	10/2000	Asaba et al.				
M	6,139,761	10/2000	Ohkuma				
M	6,143,190	11/2000	Yagi et al.				
M	6,305,080 B1	10/2001	Komuro et al.				
FOREIGN PATENT DOCUMENTS							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT	
M	JP 10-181032	07/1998	Japan				
M	JP 6-347830	12/1994	Japan				
M	JP 9-11479	01/1997	Japan				
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
M	E. Bassous, "Fabrication of Novel Three-Dimensional Microstructures by the Anisotropic Etching of (100) and (110) Silicon," IEEE Transactions on Electron Devices, October, 1978, Vol. ED-25, No. 10, pgs. 1178-1185.						
*Note: U.S. counterpart patents also submitted (see text of IDS).							
EXAMINER	<i>Robert Collet</i>	DATE CONSIDERED <i>10/9/04</i>					

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicants.
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